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Electrooptics device and mfg method, electronic instrument

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An electro-optical device and a method of manufacturing the same capable of suppressing an influence due to an irregularity of a switching element or a wiring line on a functional element is provided. An organic EL apparatus includes on a substrate P an organic EL device 200, a wiring for supplying a power to the organic EL device 200, and a switching element 143. An insulating layer 100 is formed on the substrate P, and a

concave part is formed in the insulating layer 100 to dispose the switching element 143.

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